



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/212,726  
Filing Date .... December 15, 1998  
Inventor .... Klaus Florian Schuegraf  
Assignee .... Micron Technology, Inc.  
Group Art Unit .... 2813  
Examiner .... Erik J. Kielin  
Attorney's Docket No. .... MI22-1098  
Title: Semiconductor Processing Methods of Chemical Vapor Depositing SiO<sub>2</sub> on  
a Substrate

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9/26/02  
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**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References -See Attached Form PTO-1449

The Examiner's attention is directed to the reference which is listed on the attached Form PTO-1449, a copy of the abstract of which is attached. No admission is made regarding whether the submitted reference is prior art.

Citation of the referenced art is respectfully requested.

Respectfully submitted,

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TECHNOLOGY CENTER 2800

Dated: September 17, 2002

By: Jennifer J. Taylor  
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